

Receipt

533 Rec'd PCT/PTO 12 JUL 2002



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Reply, Application of

Docket No: Q60716

Hiromoto OHNO, et al.

Appln. No.: 10/088,306

Group Art Unit: 3749

Confirmation No.: 2926

Examiner: Not Yet Assigned

Filed: March 18, 2002

For: CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT

REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT

Commissioner for Patents
Office of Initial Patent Examination
Customer Service Center
Washington, D.C. 20231

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TECHNOLOGY CENTER R3700

Sir:

We enclose a copy of the Official Filing Receipt for the above-identified application and request the following correction(s):

Applicant(s)

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Shuji Yoshida, Kanagawa, JAPAN
Manabu Ohhira, Kanagawa, JAPAN
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Verification for the requested correction(s) is indicated on the original Declaration and Power of Attorney filed March 18, 2002.

Respectfully submitted,

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Date: July 12, 2002

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APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
10/088,308	06/11/2002	3749	1262	Q60716	1	36	4

CONFIRMATION NO. 2926

 23373
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FILING RECEIPT



OC00000008249357

Date Mailed: 06/11/2002

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

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Domestic Priority data as claimed by applicant

THIS APPLICATION IS A 371 OF PCT/JP01/06164 07/17/2001 ✓
 WHICH CLAIMS BENEFIT OF 60/230,811 09/07/2000 * ✓
 AND CLAIMS BENEFIT OF 60/261,265 01/16/2001 * ✓
 (*)Data provided by applicant is not consistent with PTO records.

Foreign Applications

JAPAN 2000-217610 07/18/2000 ✓
 JAPAN 2000-397269 12/27/2000 ✓
 JAPAN 2001-189388 06/22/2001 ✓

Projected Publication Date: To Be Determined - pending completion of Security Review

Non-Publication Request: No

Early Publication Request: No

Title

Cleaning gas for semiconductor production equipment ✓

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Preliminary Class

034

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